



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q67844

Takako SUZUKI, et al.

Appln. No.: 10/084,204

Group Art Unit: 1752

Confirmation No.: 6177

Examiner: John S. Y. Chu

Filed: February 28, 2002

For: POSITIVE PHOTORESIST COMPOSITION AND PROCESS FOR FORMING RESIST  
PATTERN USING SAME

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one (1) month, extending the time for responding to the Office Action of May 18, 2004 to September 20, 2004 (September 18, 2004 being a Saturday).

A check for the statutory fee of \$110.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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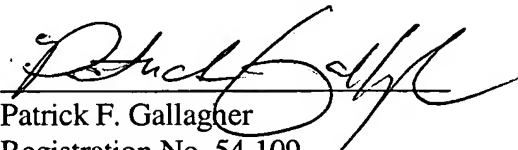
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WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

  
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Date: September 20, 2004